# Combinatorial Approach for Single-Crystalline TaON Growth: Epitaxial $\beta$ -TaON (100)/ $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012)

K. V. L. V. Narayanachari, D. Bruce Buchholz, Elise A. Goldfine, Jill K. Wenderott, Sossina M. Haile, and Michael J. Bedzyk\*



**ABSTRACT:** The photocatalyst  $\beta$ -TaON is of interest due to promising properties, such as stability, suitable band gap for visible light, and carrier mobility. We implemented a combinatorial, material discovery approach that used pulsed laser deposition (PLD) for thin-film growth, X-ray diffraction (XRD) for phase determination, and machine learning for data reduction. A lateral compositional gradient of TaO<sub>x</sub>N<sub>y</sub> was grown across the surface of an  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) wafer. After annealing, XRD scattering patterns were collected across the lateral gradient. Unsupervised machine learning separated the XRD data into four clusters (phases); one of which turned out to be the desired monoclinic  $\beta$ -TaON phase. Using high-resolution XRD, we determined that the  $\beta$ -TaON region of the film was a 260 Å thick single-crystal epitaxial with the substrate, having out-of-plane  $\beta$ -TaON (100)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) and inplane  $\beta$ -TaON (010)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (210). X-ray reflectivity (XRR) analysis of the



 $\beta$ -TaON region of the film showed an electron density matching that expected for  $\beta$ -TaON. X-ray photoelectron spectroscopy (XPS) showed a Ta<sup>5+</sup> valence state in the  $\beta$ -TaON region of the film. This combinatorial approach, which produces a library of phases on a single wafer, proved to be very efficient for the growth of a material's phase of interest.

**KEYWORDS:**  $\beta$ -TaON, combinatorial synthesis, thin film, PLD, XRD, machine learning

# INTRODUCTION

Increasing global energy demands and environmental concerns due to fossil fuel consumption obligates the search for renewable energy sources, such as solar energy, which is both clean and abundant. Among the various methods for solar energy conversion is the production of oxygen and hydrogen by water splitting. The use of semiconductor materials for overall water splitting (OWS) into  $O_2$  and  $H_2$  is an uphill reaction with a standard Gibb's free energy of 237 kJ mol<sup>-1</sup> = 2.46 eV molecule<sup>-1,1-3</sup> When the semiconductor absorbs a photon with an energy higher than the band gap, an electron is excited to the conduction band, leaving a hole in the valence band. The excited electrons and holes separately diffuse to the surface of the semiconductor and participate in oxidation and reduction reactions that produce oxygen and hydrogen.<sup>4-6</sup>

Since the first breakthrough of photocatalytic water splitting by Honda and Fujishima,<sup>7</sup> many semiconductor materials have been studied for this application. This includes transition metal oxides, along with oxynitrides, which are attracting much attention recently.<sup>8–18</sup> Many of the transition metal oxides are suitable materials due to abundance, stability, and nontoxicity, but their poor charge conductivity and wider band gaps result in lower efficiencies and the requirement of the higher energy/ UV portion of the solar spectrum. Incorporation of nitrogen into the transition metal oxides is one way of reducing the band gap because of the shallow nature of the N 2p orbitals compared to the O 2p orbitals.  $^{19-21}$ 

Tantalum oxynitride with a monoclinic crystal structure ( $\beta$ -TaON) is a very attractive material for this photocatalytic application.<sup>22,23</sup>  $\beta$ -TaON has a band gap of 2.5 eV, which is within the visible part of the solar spectrum. The valence band maximum (VBM) and conduction band minimum (CBM) of this material are optimally positioned with respect to the reduction and oxidation potentials of the water-splitting reaction.<sup>3,11,24</sup>

Apart from the electronic structure of the photocatalytic material, the functionality strongly depends on the morphology of the material.<sup>25,26</sup> High-quality single-crystalline materials are required to reduce recombination centers (grain boundaries and other point defects) and to simplify the study of the structural and functional characteristics of the material. For example, the availability of single-crystalline TiO<sub>2</sub> made it possible to study the charge transport, recombination

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**Figure 1.** Depiction of the  $TaO_xN_y$  thin film grown by PLD on  $\alpha$ -Al<sub>2</sub>O<sub>3</sub>(012). (a) Deposition of the  $TaO_x/TaN_y$  linear composition gradient film. (b)  $TaO_xN_y$  thin film with a composition gradient along the *Y*-direction and uniform along the *X*-direction.

mechanisms, and the effect of surface orientation on the photocatalytic activity.<sup>27–29</sup> Several attempts have been made to grow thin films of TaON using sputter deposition,<sup>30–33</sup> pulsed laser deposition (PLD),<sup>34</sup> and ammonolysis of  $Ta_2O_5$ .<sup>1,35–37</sup>

There are several crystalline phases of TaO<sub>x</sub>N<sub>y</sub>.<sup>4,38</sup> The 1:1:1 composition of TaON is known to exist in three polymorphs: monoclinic  $\beta$ -TaON ( $P2_1/c$ ),<sup>38,39</sup> metastable  $\gamma$ -TaON (C2/m),<sup>38,39</sup> and  $\delta$ -TaON ( $I4_1/amd$ ).<sup>40,41</sup> Among these phases,  $\beta$ -TaON is semiconducting and the most stable.  $\beta$ -TaON is a baddeleyite-type structure and isostructural to ZrO<sub>2</sub>.

To achieve single-crystal epitaxy of a desired film, a substrate needs to be chosen with a chemical and geometrical match at the film/substrate interface.<sup>42</sup> For  $\beta$ -TaON, *r*-plane sapphire ( $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012)) was chosen, which has a pseudo rectangular surface unit cell with lattice constants  $a_s = 5.13$  Å and  $b_s = 4.76$  Å that reasonably match the rectangular surface unit cell of  $\beta$ -TaON (100) with lattice constants  $a_s = 5.19$  Å and  $b_s = 5.04$  Å.

For efficiency, our material development process combined a compositional spread in the synthesis step with highthroughput measurements of the produced phases. 43-46 Machine learning-based big data techniques were used to convert a large set of experimental data into actionable small clusters.<sup>47–50</sup> In the process of trying to grow a  $\beta$ -TaON thin film, the stoichiometry (O/N) is crucial to obtaining the preferred phase.<sup>24</sup> Instead of realizing and optimizing the O/N ratio from a large set of individual thin-film samples, we deposited a lateral compositional graded thin-film sample using multitarget PLD.<sup>51</sup> Ideally, the composition should range from TaN at one edge of the substrate to Ta2O5 at the opposite edge. The use of high-throughput, small-area X-ray diffraction (XRD) measurements combined with machine learning-based analysis made it possible to identify the desired  $\beta$ -TaON phase on the compositionally graded sample.

#### **EXPERIMENTAL METHODS**

 $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) (*r*-plane sapphire) substrates (25 × 25 mm<sup>2</sup>) were precleaned with acetone and isopropanol before the introduction into the PVD Products PLD/MBE 2300 chamber, where the TaO<sub>x</sub>/TaN<sub>y</sub> linear composition gradient films were grown on the substrates by PLD (see Figure 1).

The PLD system uses a 248 nm KrF excimer laser with a 25 ns pulse duration. The dense hot-pressed PLD targets of  $Ta_2O_5$  and TaN were purchased from Kurt J. Lesker Company. The deposition ambient was 10 mTorr  $N_2$ , and the substrate deposition temperature was 675 °C.

The laterally graded film was obtained using an alternating layerby-layer technique in combination with a traveling mask.<sup>43</sup> Each  $TaO_x$ layer was deposited using 100 laser pulses from the  $Ta_2O_5$  target, while the mask swept laterally across the substrate in 20 s (see Figure 1a). Similarly, each  $TaN_y$  layer was deposited using 300 laser pulses from the TaN target, while the mask swept in the opposite direction across the substrate in 20 s. The thicknesses of individual layers at the two extreme lateral ends, where the composition was 100%  $TaO_x$  or 100%  $TaN_w$  were 1–2 Å. The process of alternating between  $TaO_x$  and TaN<sub>y</sub> wedge-shaped layers was repeated 150 times. A detailed description is included in the Supporting Information. After deposition, the thin-film sample was annealed in a tube furnace at 1000 °C for 2 h in nitrogen (99.999%) at ambient pressure to promote grain growth. Based on X-ray reflectivity (XRR), the total film thickness was 260 Å at the TaN<sub>y</sub> and 160 Å at the TaO<sub>x</sub> end of the compositional gradient.

Small-area X-ray diffraction (XRD) measurements used a 3 KW Cu target Rigaku Smartlab with a polycapillary optic (CBO-f unit) that focused the line source from the X-ray anode to a spot of 400  $\mu$ m diameter at the sample. A two-dimensional (2D) HyPix 3000 detector was used to collect the scattering patterns in a  $\theta/2\theta$  specular reflection geometry. (See Figure S2 for the X-ray experimental setup.) The 2D scattering pattern was converted to a one-dimensional (1D) function I(Q), where the modulus of the scattering vector  $Q = 4\pi \sin(\theta)/\lambda$ ,  $2\theta$ is the scattering angle, and  $\lambda$  is the X-ray wavelength. The sample was aligned in the incident beam direction to minimize the X-ray footprint in the composition gradient direction (Y-direction) to a value of 400  $\mu$ m. Data were collected in 71 steps along this direction. To determine the in-plane epitaxial orientation of the film relative to the substrate lattice, we used parallel beam optics from a 9 KW Cu rotating anode SmartLab to find the  $\chi$  and  $\phi$  angles at which offspecular reflections occurred for the substrate and film. Tilt angle  $\chi$  is the angle between the desired off-specular hkl reciprocal space vector and the Al<sub>2</sub>O<sub>3</sub> (012) vector. Angle  $\phi$  is the azimuthal rotation about the Al<sub>2</sub>O<sub>3</sub> (012) vector. For increasing the in-plane resolution,  $0.5^{\circ}$ soller slits were used on the incident and detector arms of the diffractometer. The incident beam slits limited the beam width to a 3 mm wide footprint on the sample centered at the location of interest. This same 9 KW SmartLab was also used for the specular low-angle X-ray reflectivity measurements.

## RESULTS AND DISCUSSION

Figure 2a shows the specular X-ray scattered intensity as a function of  $Q_z$  and lateral position (*Y*) along the compositional gradient direction with a pitch of 350  $\mu$ m.

Using fuzzy c-means (FCM) clustering, we developed a Python code for clustering the XRD data based on the similarity of the diffraction patterns.<sup>52</sup> Using unsupervised machine learning, all of the XRD patterns were grouped into four clusters (see the Supporting Information for details on clustering). Peak positions from each cluster are compared to patterns in the International Centre for Diffraction Data-Powder Diffraction File (ICDD-PDF) database and matched to Ta<sub>2</sub>O<sub>5</sub> and TaON phases, as shown in Figure 3. In particular, cluster 0, which extends from Y = -12.5 to -6 mm, encompassing the nitrogen-rich region of the composition gradient, is dominated by  $\beta$ -TaON. Only a very minor contribution from Ta<sub>2</sub>O<sub>5</sub> is evident in this cluster. In contrast, clusters 1, 2, and 3 are all largely described by Ta<sub>2</sub>O<sub>5</sub>, with discrepancies due to differences in crystallinity and orientation. Because of peak overlap in the XRD data, the presence of nitride phases (TaN,  $Ta_3N_5$ ) cannot be ruled out. However, as shown in Figure S6, we can rule out these phases based on XPS analysis. Rietveld refinement of the specular XRD data on the nitrogen-rich end of the gradient shows that the pattern can be



**Figure 2.** Focused beam XRD data. (a) Specular XRD intensities I(Q) collected as a function of Y along the composition gradient of the film. The highest intensities at  $Q_Z = 1.81$  and 3.61 Å<sup>-1</sup> are from the Al<sub>2</sub>O<sub>3</sub> (012) and (024) Bragg peaks. (b) XRD patterns from the film are separated into four clusters by unsupervised machine learning. Membership represents the probability of a pattern belonging to a cluster.



**Figure 3.** Representative XRD intensity patterns from Figure 2 for the four clusters with identified peaks from the Ta<sub>2</sub>O<sub>5</sub> and TaON phases. The peaks in cluster 0 at  $Q_Z = 2.57$  and 3.84 Å<sup>-1</sup> correspond to the  $\beta$ -TaON (200) and (300) planes, respectively. The high-intensity peaks at 1.81 and 3.61 Å<sup>-1</sup> are from the single-crystal substrate  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) and (024) planes, respectively. Each XRD intensity curve is offset by 1 decade for purposes of clarity. <sup>‡</sup> refers to unidentified peaks.

described as 99%  $\beta$ -TaON with a trace amount of Ta<sub>2</sub>O<sub>5</sub> (see Figure S5). Even on the nitrogen-rich end, there is substantial oxygen incorporation that occurred during film growth from TaN PLD target and/or postgrowth annealing.

The relatively high intensities from the (200) and (300) peaks of  $\beta$ -TaON in cluster 0 at  $Q_z = 2.57$  and 3.84 Å<sup>-1</sup> point to the possibility of texture or single-crystal epitaxy in the

(100) direction. To evaluate this possibility, we performed additional diffraction studies (Figures 4 and 5) probing an area of the film entirely within cluster 0, i.e., centered at Y = -8.7 mm, using a parallel beam X-ray setup with a beam width of 3 mm along the Y-direction.

We performed a higher-resolution longitudinal Qz scan (Figure 4a) and a transverse  $Q_r$  scan (Figure 4b) through the (200) peak. The calculated crystallite sizes in lateral and normal directions on the film, from FWHM of the  $Q_{z}$  and  $Q_{yy}$ are 251 and 105 Å, respectively. The narrow width of the substrate rocking curve, as shown in Figure 4c, confirms that the broadening of the film peaks was not due to instrument resolution. To explore if the peak in the  $Q_r$  scan (Figure 4b) indicates single-crystal epitaxy or just texture; we performed  $\varphi$ scans at the off-specular  $\beta$ -TaON (130), (111), and (110) Bragg conditions (see Figure 5a). Comparing the peak positions in these  $\varphi$ -scans to that of the  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (113) indicates that the film is epitaxial with out-of-plane  $\beta$ -TaON  $(100)/(\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) and in-plane  $\beta$ -TaON (010)/( $\alpha$ -Al<sub>2</sub>O<sub>3</sub>  $(2\overline{1}0)$ . The stereographic projection of the *hkl* poles in Figure 5b helps explain the directional relationships between the two lattices.

For the case of single-crystal  $\beta$ -TaON (100) only, two peaks are expected in a  $\varphi$ -scan of the (111) reflection (shown in Figure 5b separated by  $\Delta \phi = 91.6^{\circ}$ ), whereas four peaks are present in the experiment (see Figure 5a). This is due to nucleation and growth leading to two morphologically equivalent in-plane orientations for  $\beta$ -TaON (100)/ $\alpha$ -Al<sub>2</sub>O<sub>3</sub>(012), one orientation with  $\beta$ -TaON(010)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub>(100) and the other orientation with  $\beta$ -TaON(010)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub>(100) as represented in Figure 6b. As a result of this twinning, a mirror symmetry in the  $\varphi$ -scan of (111) poles is observed instead of just two peaks separated by 91.6°.

After confirming the  $\beta$ -TaON crystalline phase presence and epitaxial relations, the  $\beta$ -TaON density was compared to that of the bulk crystal. A low-angle X-ray reflectivity (XRR) measurement was performed at the location of the  $\beta$ -TaON on the compositionally graded sample using a parallel beam setup with an X-ray beam width of 3 mm. As shown in Figure 7, along with the fit to the XRR, data determines the electron density profile.<sup>53</sup> From this fit, we find a film thickness of 260 Å and electron densities that match the expected bulk values of 2.65 and 1.19 e Å<sup>-3</sup> for  $\beta$ -TaON and  $\alpha$ -Al<sub>2</sub>O<sub>3</sub>, respectively. The film thickness closely matches the out-of-plane singlecrystal domain size of 251 Å obtained from Figure 4a  $Q_z$  scan, further confirming the single-crystal nature of the film in this region.



**Figure 4.** Parallel beam XRD data from the location centered at Y = -8.65 mm (with a breadth of 3 mm). (a)  $\beta$ -TaON (200) peak from  $\theta/2\theta$  scan with a full width at half-maximum (FWHM)  $\Delta Q_z = 0.025$  Å<sup>-1</sup>, which corresponds to an out-of-plane single-crystal domain size  $D_Z = 251$  Å. (b)  $\beta$ -TaON (200) peak from  $\omega$ -scan with FWHM  $\Delta Q_x = 0.06$  Å<sup>-1</sup>, corresponds to in-plane single-crystal domain size  $D_X = 105$  Å. (c)  $\omega$ -scan of  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) with FWHM  $\Delta Q_x = 0.0027$  Å<sup>-1</sup>, corresponds to diffractometer resolution.



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**Figure 5.** Local XRD measurements on the graded sample at Y = -8.65 mm, using a parallel beam setup with an X-ray beam width of 3 mm. (a)  $\varphi$ -Scans representing in-plane orientation relation between the substrate (113) and the single-crystalline  $\beta$ -TaON film. (b) Stereographic projection of *hkl* poles for  $\beta$ -TaON (black labels) and  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (red labels) with  $\beta$ -TaON (100)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) and  $\beta$ -TaON (010)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (210).



**Figure 6.** (a) Unit cells of  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> and monoclinic  $\beta$ -TaON. (b) Projection of  $\beta$ -TaON (100)/ $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) epitaxial relation along the film -b-axis direction (left), +b-axis direction (right), which are parallel to the substrate *a*-axis direction. (c) Same as (b), but projection along the film +*c*-axis direction, which is along the substrate [12–1] direction.



**Figure 7.** Specular XRR data (solid circles) and best fit for the  $\beta$ -TaON (260 Å thickness) on  $\alpha$ -Al<sub>2</sub>O<sub>3</sub>. Inset is the electron density profile determined from the reflectivity fit. Expected densities for the TaON and  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> are shown as dotted lines. XRR was measured at the  $\beta$ -TaON phase location, Y = -8.65 mm.

# CONCLUSIONS

In summary, PLD film growth from TaN and Ta<sub>2</sub>O<sub>5</sub> end members and high-throughput XRD characterization combined with machine learning-based data reduction techniques made the identification of epitaxial  $\beta$ -TaON(100)/ $\alpha$ -Al<sub>2</sub>O<sub>3</sub>(012) possible in an efficient manner. Small-area X-ray diffraction and XPS studies showed  $\beta$ -TaON as the dominant phase at the nitrogen-rich end of the film, with Ta<sub>2</sub>O<sub>5</sub> occurring at the oxygen-rich end. X-ray  $\varphi$ -scans of the offspecular reflections from the film and substrate at a  $\beta$ -TaON dominated position showed the epitaxial relation  $\beta$ -TaON (100)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (012) and  $\beta$ -TaON (010)// $\alpha$ -Al<sub>2</sub>O<sub>3</sub> (2 $\overline{10}$ ). A fit to the specular XRR reflectivity (at this same position) yielded a film thickness of 260 Å and a calculated electron density of 2.63 e Å<sup>-3</sup>, matching with the expected value 2.65 e Å<sup>-3</sup> for  $\beta$ -TaON. Our results indicate that graded film synthesis, in tandem with high-throughput XRD and machine learning tools, provides a novel approach to effectively and efficiently identify synthesis routes to desired materials.

## ASSOCIATED CONTENT

#### **Supporting Information**

The Supporting Information is available free of charge at https://pubs.acs.org/doi/10.1021/acsaelm.0c00622.

Detailed synthesis methods for composition gradient, description of small-area XRD setup, specular XRD of as-deposited and annealed films, details of ML-based clustering, and Rietveld refinement of GI-XRD data (PDF)

## AUTHOR INFORMATION

## **Corresponding Author**

Michael J. Bedzyk – Department of Materials Science and Engineering and Department of Physics and Astronomy, Northwestern University, Evanston, Illinois 60208, United

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*States;* orcid.org/0000-0002-1026-4558; Email: bedzyk@ northwestern.edu

#### Authors

- K. V. L. V. Narayanachari Department of Materials Science and Engineering, Northwestern University, Evanston, Illinois 60208, United States; orcid.org/0000-0002-2033-8717
- **D. Bruce Buchholz** Department of Materials Science and Engineering, Northwestern University, Evanston, Illinois 60208, United States
- Elise A. Goldfine Department of Materials Science and Engineering, Northwestern University, Evanston, Illinois 60208, United States
- Jill K. Wenderott Department of Materials Science and Engineering, Northwestern University, Evanston, Illinois 60208, United States
- Sossina M. Haile Department of Materials Science and Engineering, Northwestern University, Evanston, Illinois 60208, United States; © orcid.org/0000-0002-5293-6252

Complete contact information is available at: https://pubs.acs.org/10.1021/acsaelm.0c00622

## Notes

The authors declare no competing financial interest.

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